L Number	Hits	Search Text	DB	Time stamp
1	2	("5872880").PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:29
2	2	("6212151").PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:33
3	1		USPAT	2003/12/10 12:30
4	1		USPAT	2003/12/10 12:31
5	1		USPAT	2003/12/10 12:31
6	1		USPAT	2003/12/10 12:32
7	18749	mirror and hinge	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:33
8	78885	369/$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:34
9	16052	mirror near7 substrate	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:39
10	778	(mirror and hinge) and (mirror near7 substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:34
11	22	369/$.ccls. and ((mirror and hinge) and (mirror near7 substrate))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:58
12	46513	mirror near7 rotat$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:40
13	16	(369/$.ccls. and ((mirror and hinge) and (mirror near7 substrate))) and (mirror near7 rotat$5)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:45
14	254	(micro or microfabricat$5) near5 hinge	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 13:52
16	1	369/$.ccls. and ((mirror near7 substrate) and ((micro or microfabricat$5) near5 hinge))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:47
15	83	(mirror near7 substrate) and ((micro or microfabricat$5) near5 hinge)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:47
17	40468	rotat$5 near4 mirror	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:59

18	1848	(mirror and hinge) and (rotat$5 near4 mirror)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 12:59
19	37	369/$.ccls. and ((mirror and hinge) and (rotat$5 near4 mirror))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 13:03
20	2	("6212151").PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 13:16
21	1		USPAT	2003/12/10 13:03
22	1		USPAT	2003/12/10 13:03
23	1		USPAT	2003/12/10 13:04
24	1		USPAT	2003/12/10 13:04
25	1		USPAT	2003/12/10 13:04
26	2	("4626066").PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 13:17
27	4508	(micro or microfabricat$5) near5 mirror	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 13:54
28	22678	mask and (dry adj1 etching) and substrate	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 14:01
29	105	((micro or microfabricat$5) near5 mirror) and (mask and (dry adj1 etching) and substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 13:56
30	14	((micro or microfabricat$5) near5 hinge) and (((micro or microfabricat$5) near5 mirror) and (mask and (dry adj1 etching) and substrate))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 14:00
31	115	((micro or microfabricat$5) near5 hinge) and ((micro or microfabricat$5) near5 mirror)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 14:00
32	34905	(dry adj1 etching) and substrate	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 14:01
33	15	(((micro or microfabricat$5) near5 hinge) and ((micro or microfabricat$5) near5 mirror)) and ((dry adj1 etching) and substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/10 14:01